

FIG. 1

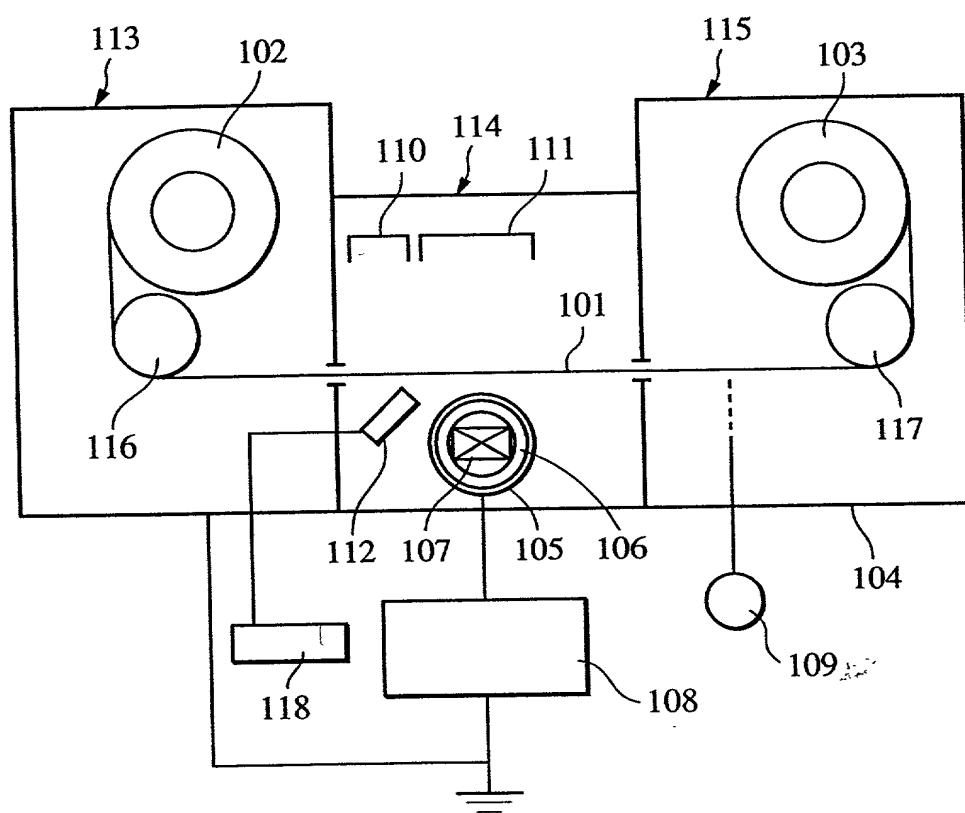


FIG. 2

GAS FLOW RATE CHANGE RESULTING BY INVENTIVE METHOD

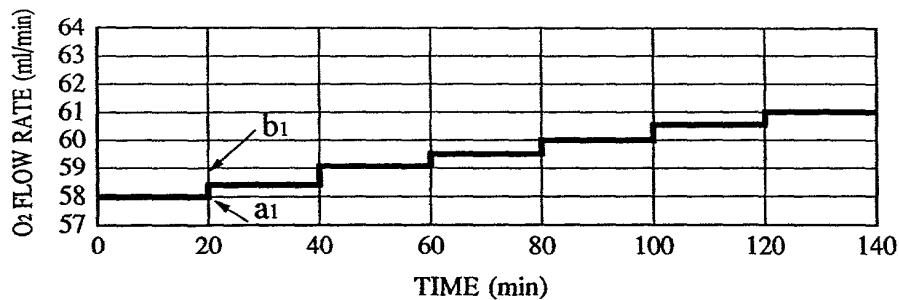


FIG. 3

FILM THICKNESS CHANGE RESULTING BY INVENTIVE METHOD

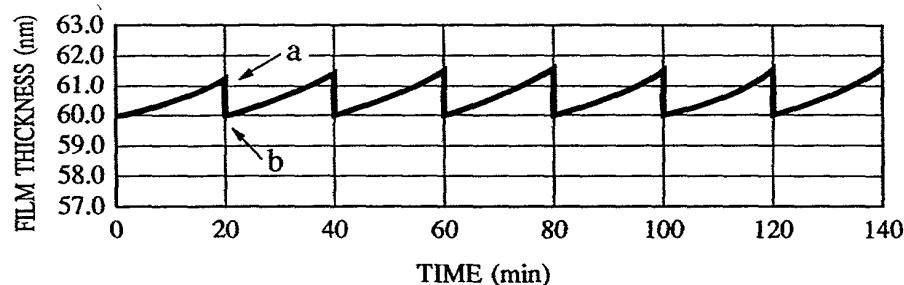
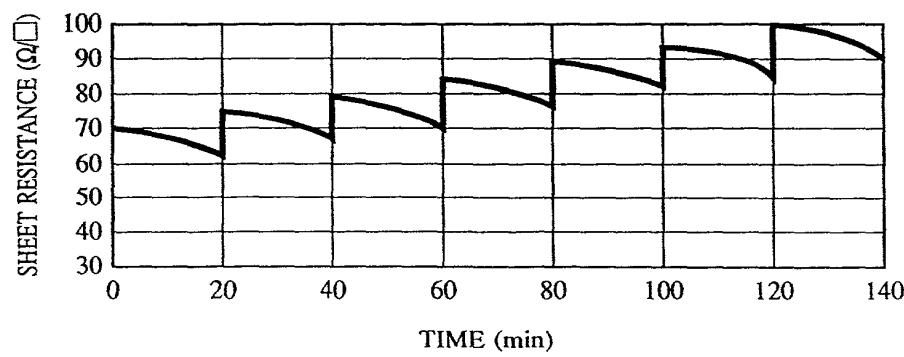


FIG. 4

SHEET RESISTANCE CHANGE RESULTING BY INVENTIVE METHOD



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FIG. 5

TRANSMITTANCE CHANGE RESULTING BY INVENTIVE METHOD

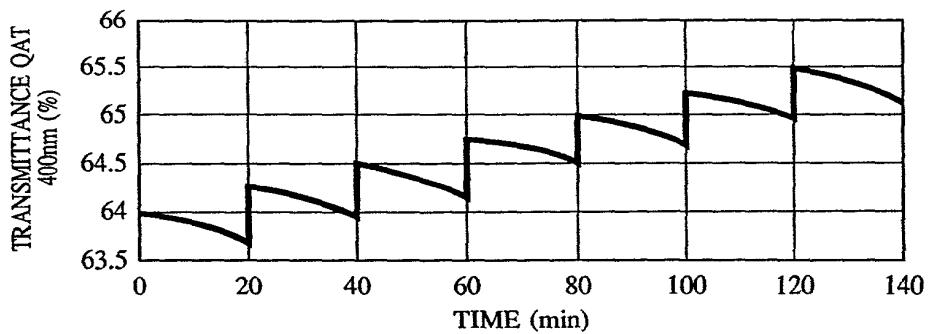


FIG. 6

CONVERSION EFFICIENCY CHANGE RESULTING BY INVENTIVE METHOD

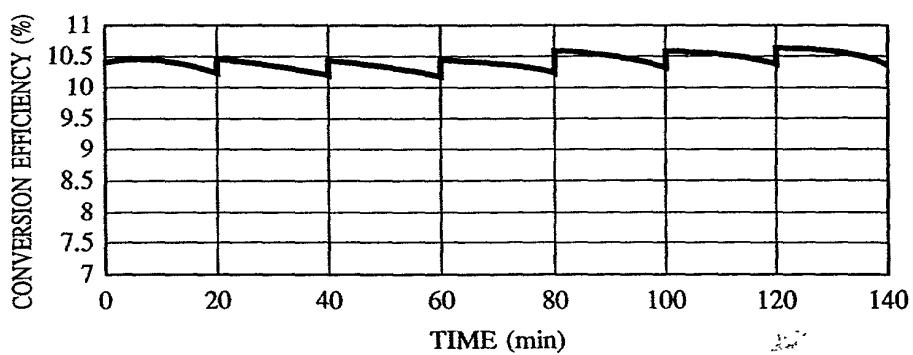
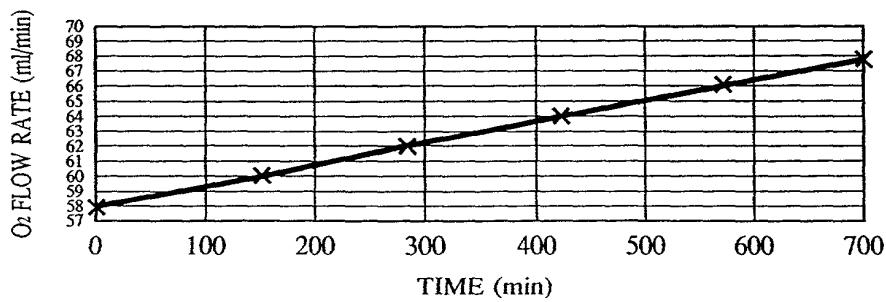


FIG. 7

GAS FLOW RATE CHANGE RESULTING BY INVENTIVE METHOD



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FIG. 8

FILM THICKNESS CHANGE RESULTING BY INVENTIVE METHOD

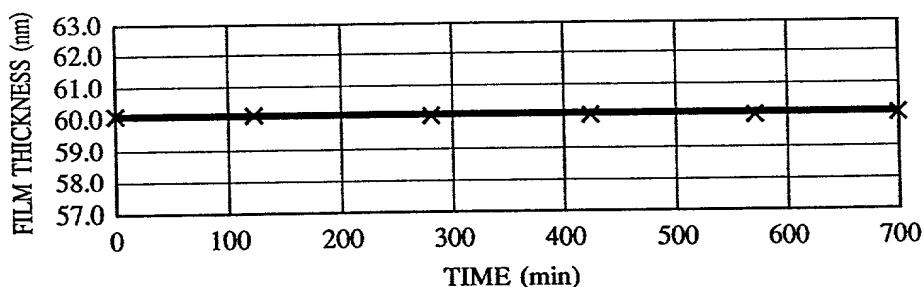


FIG. 9

SHEET RESISTANCE CHANGE RESULTING BY INVENTIVE METHOD

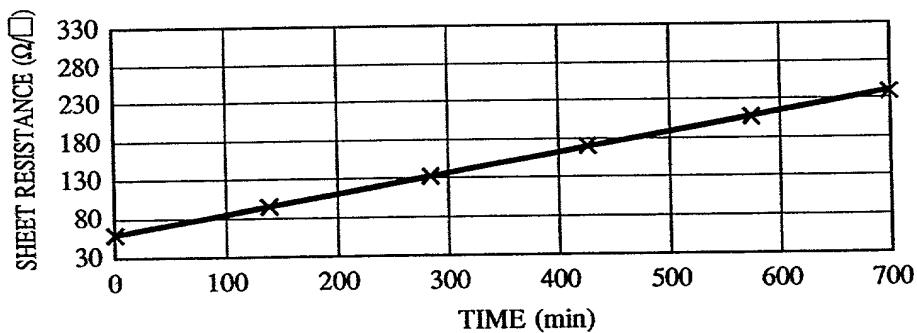


FIG. 10

TRANSMITTANCE CHANGE RESULTING BY INVENTIVE METHOD

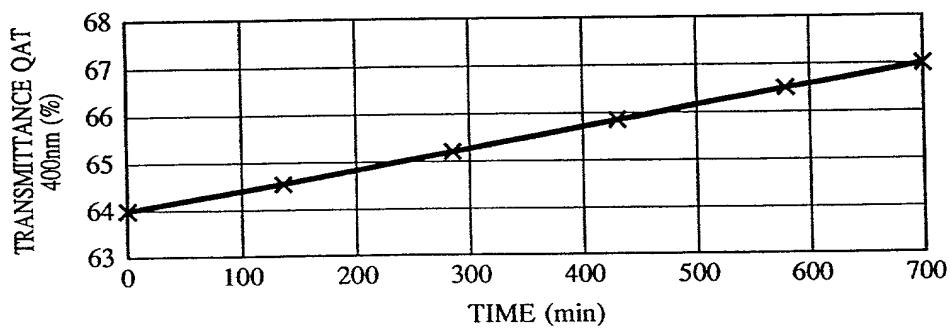


FIG. 11

CONVERSION EFFICIENCY CHANGE RESULTING BY INVENTIVE METHOD

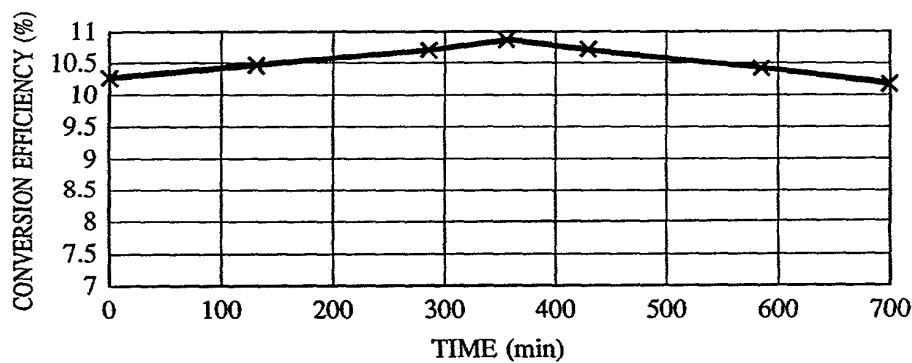


FIG. 12

CORRELATION BETWEEN TARGET VALUE AND CONVERSION EFFICIENCY

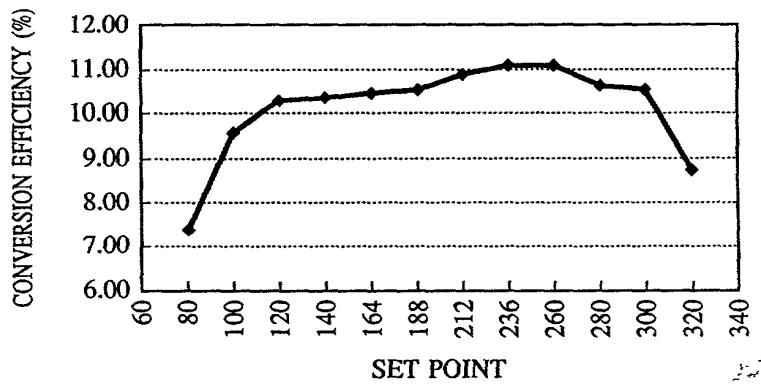


FIG. 13

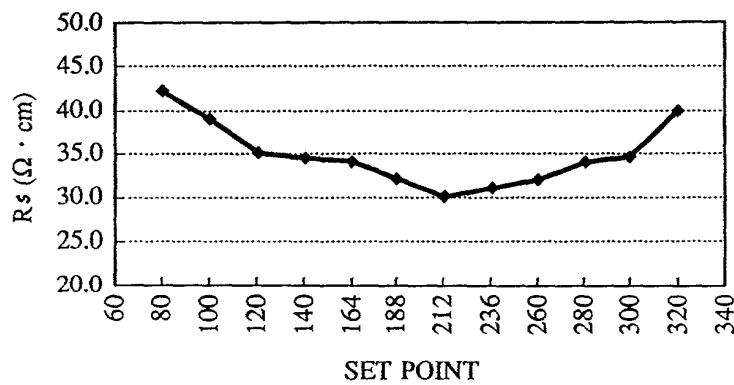
CORRELATION BETWEEN TARGET VALUE AND R_s 

FIG. 14

CORRELATION BETWEEN TARGET VALUE AND TRANSMITTANCE

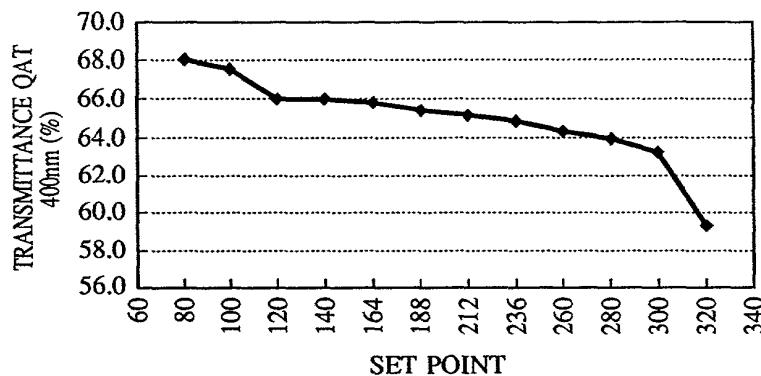


FIG. 15

CORRELATION BETWEEN TARGET VALUE AND SHEET RESISTANCE

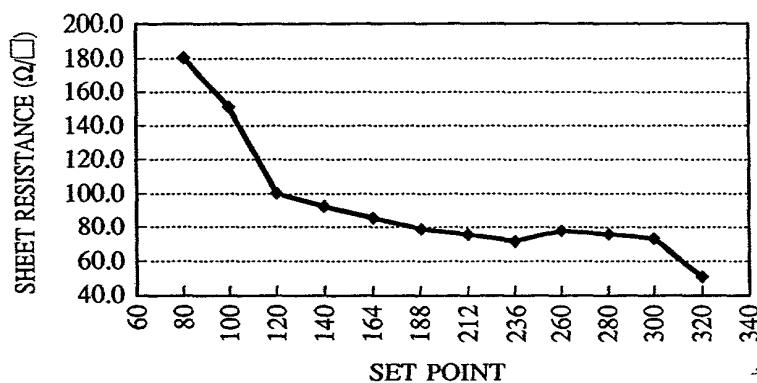
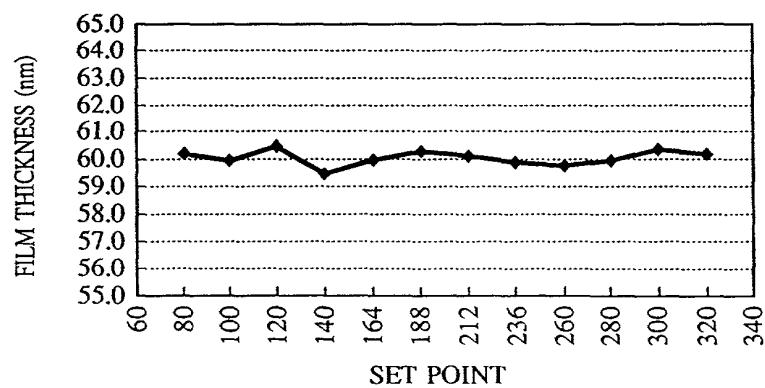


FIG. 16

CORRELATION BETWEEN TARGET VALUE AND FILM THICKNESS



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FIG. 17

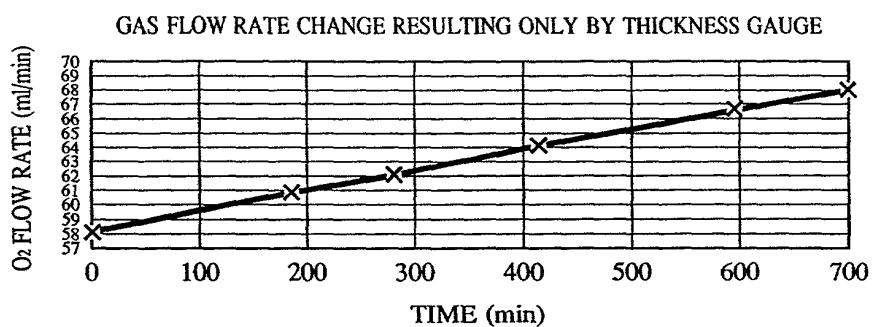


FIG. 18

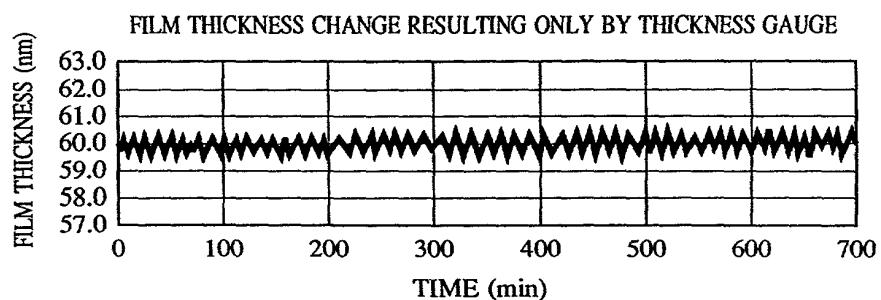
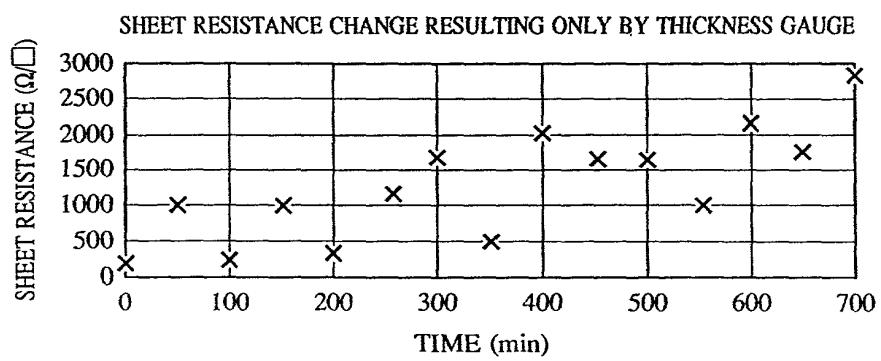


FIG. 19



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FIG. 20

TRANSMITTANCE CHANGE RESULTING ONLY BY THICKNESS GAUGE

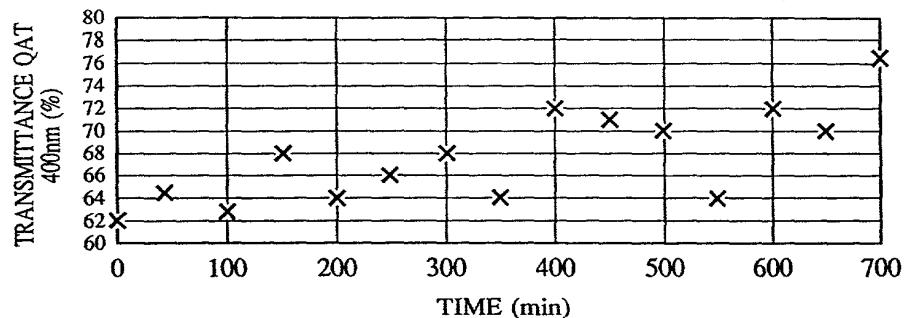


FIG. 21

CONVERSION EFFICIENCY RESULTING ONLY BY THICKNESS GAUGE

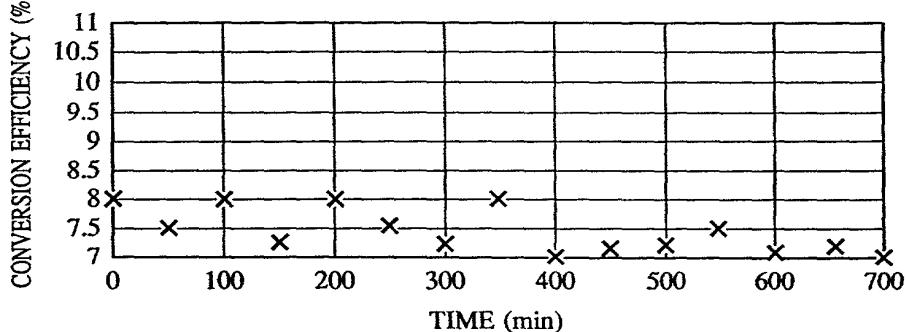


FIG. 22

FILM THICKNESS CHANGE RESULTING ONLY BY PEM CONTROL IN REACTIVE SPUTTERING

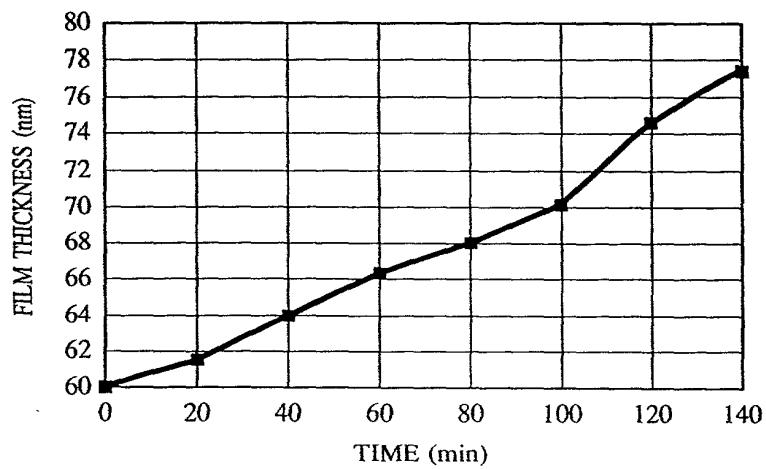


FIG. 23

